

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Branco et al.

Serial No.: 09/617,454

Filed: July 17, 2000

Title: Method for Cleaning Plasma Etch
Chamber Structures

Attorney Docket No.: CY-0015

Group Art Unit: 1746

Examiner: Smetana, J.

RESPONSE TO OFFICE ACTION5 Assistant Commissioner for Patents
Washington, D.C. 20231

Dear Sir:

10 The following is submitted in response to the Office Action dated July 2, 2002, and is
currently due October 2, 2002.

Entry of the following amendments is respectfully requested.

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37 C.F.R. §1.8

30 I hereby certify that this correspondence is being

[X] transmitted via facsimile to the United States Patent and Trademark Office to fax number: 1-703-872-9310
Date of Transmittal: October 2, 200235 [] deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for
Patents, Washington, D.C. 20231.

Date of Deposit: _____

40 Typed/Printed Name: Bradley T. SakoSignature: 